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## \*BIBDATASHEET\*

**Bib Data Sheet** 

**CONFIRMATION NO. 6050** 

Bib Data Sheet			_			
SERIAL NUMBER 10/042,271	FILING DATE 01/11/2002 RULE	CLASS 451	GROUP ART 3723	DINI	ATTORNEY OCKET NO. 66.38683CX1	
APPLICANTS						
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** CONTINUING DATA **********************************						
This application is a CON of 09/581,814 09/08/2000 PAT 6,343,976 *  (*)Data provided by applicant is not consistent with PTO records.						
** FOREIGN APPLICATIONS ************************************						
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 02/23/2002						
Foreign Priority claimed  35 USC 119 (a-d) conditions wet yes no no Met after Allowance Allowance Examiner's Signature Initial		STATE OR	SHEETS	TOTAL	INDEPENDEN	
	COUNTRY	DRAWING 0	CLAIMS 3	CLAIMS 1		
ADDRESS 020457 ANTONELLI, TERRY, 1300 NORTH SEVENT SUITE 1800 ARLINGTON , VA		<b>.</b>				

22209-3873

TITLE

Abrasive, method of polishing target member and process for producing semiconductor device					
	FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUNT No for following:	☐ All Fees			
		1.16 Fees ( Filing )			
FILING FEE		1.17 Fees ( Processing Ext. of time )			
RECEIVED 870		☐ 1.18 Fees ( Issue )			
0.0		Other			
		☐ Credit			